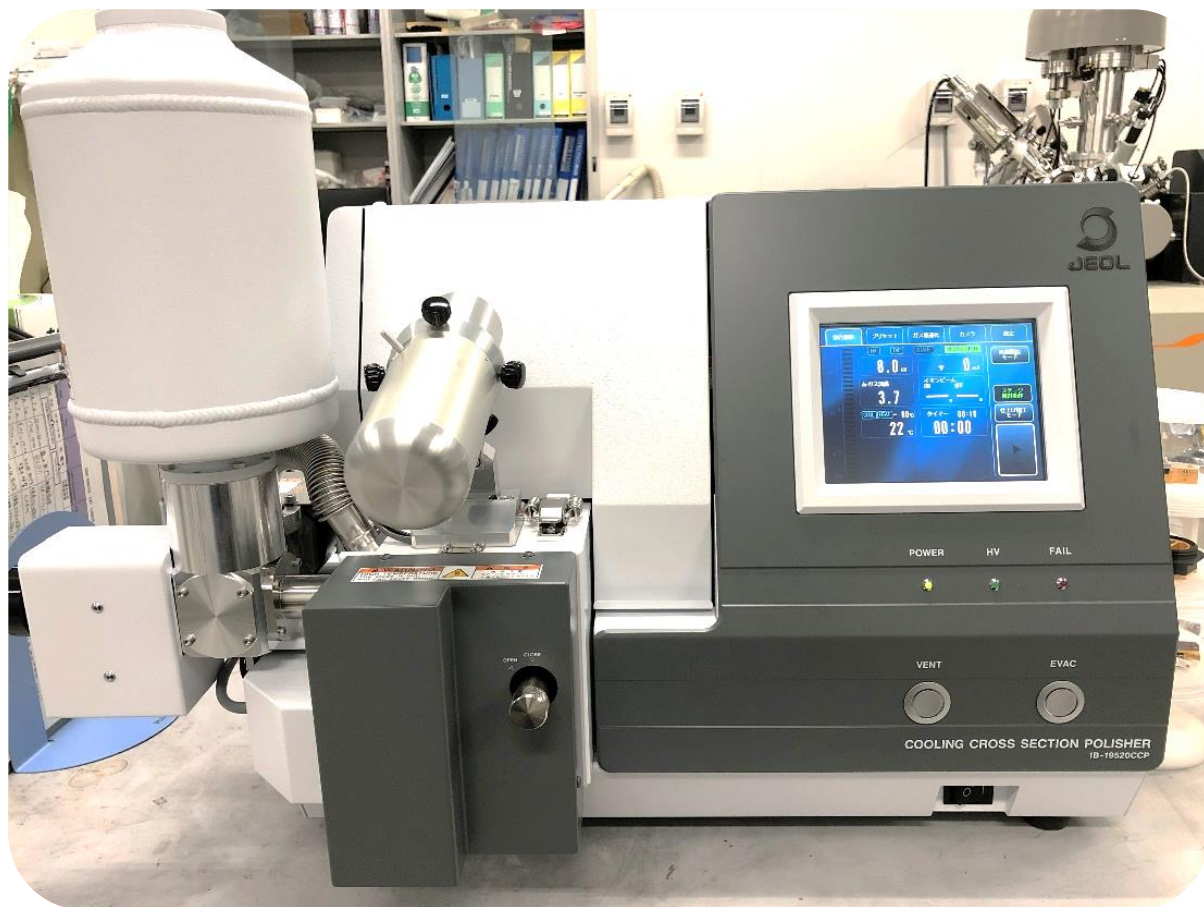


クライオクロスセクションポリッシャ
JEOL IB-19520CCP
Cryo-Cross-section Polisher



イオン加速電圧	2~8kV
ミリングスピード	500 μ m/h以上 (加速電圧8kV)
冷却温度設定範囲	-120~0 $^{\circ}$ C
試料冷却保持時間	8時間以上
最大搭載試料サイズ	11mm \times 8mm \times 3mm(断面ミリング) ϕ 40mm \times 15mm(平面ミリング)

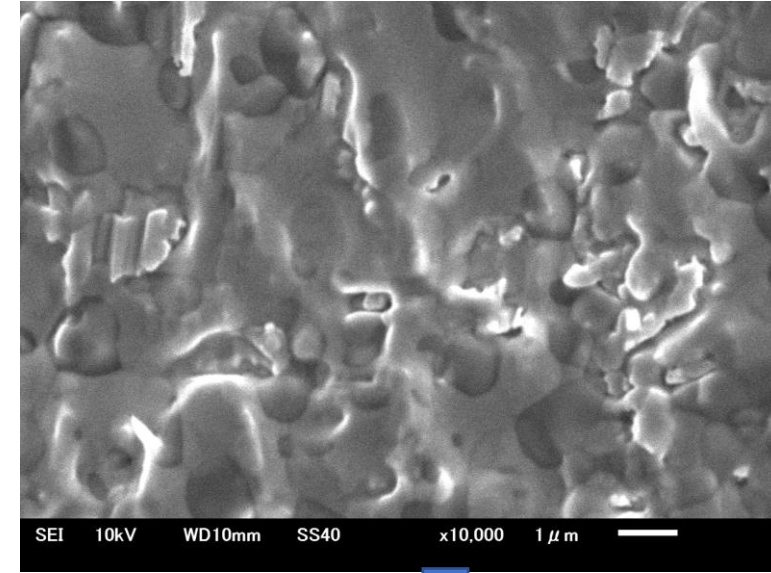
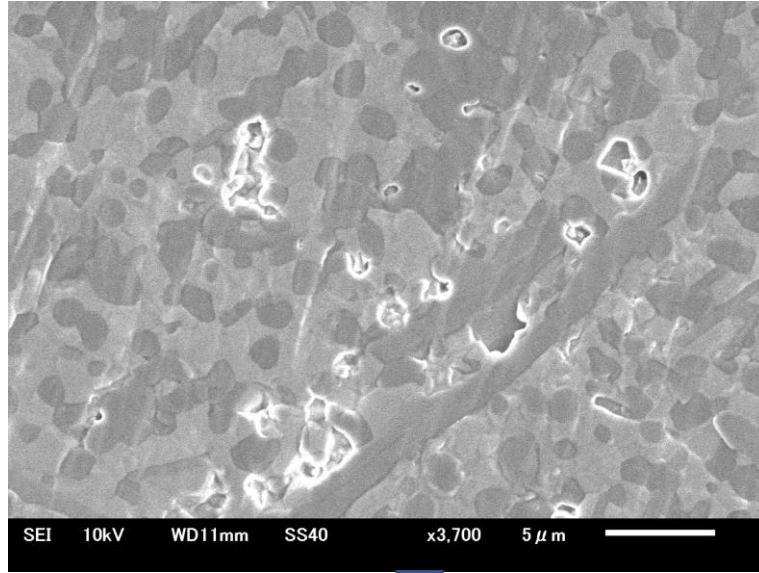
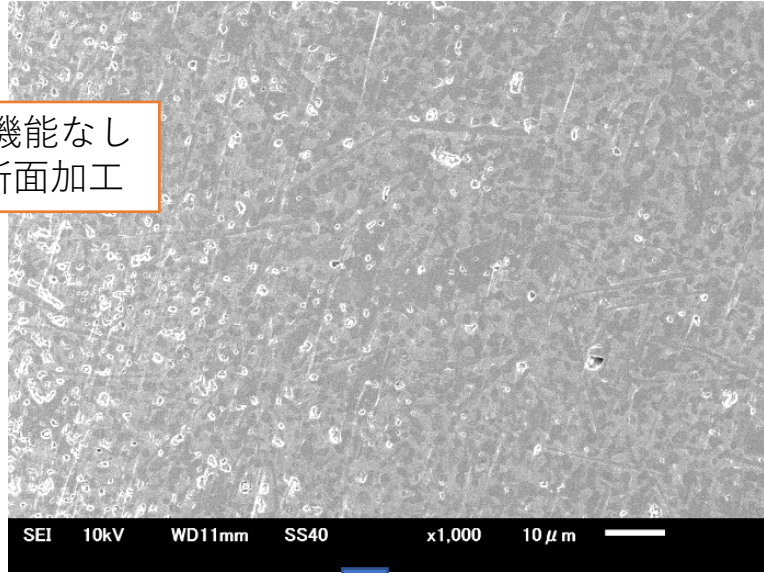
冷却以外にも様々な機能が搭載

- 自動加工開始機能
- 自動冷却加工開始機能
- 自動室温復帰機能
- プリセット機能
- 大気非曝露機能
- 間欠加工機能
- 仕上げ加工機能

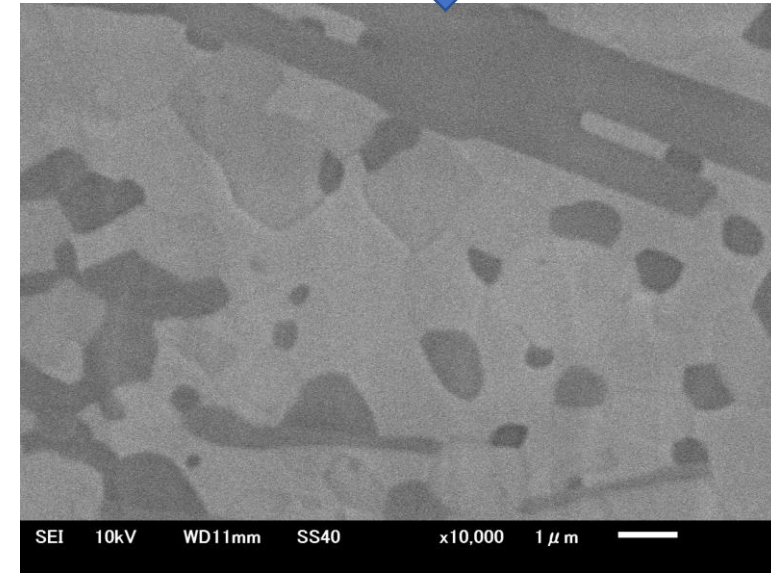
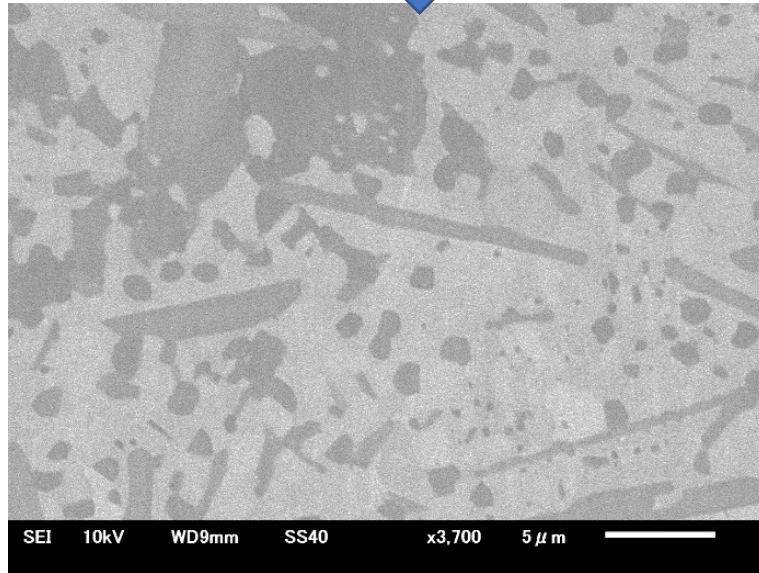
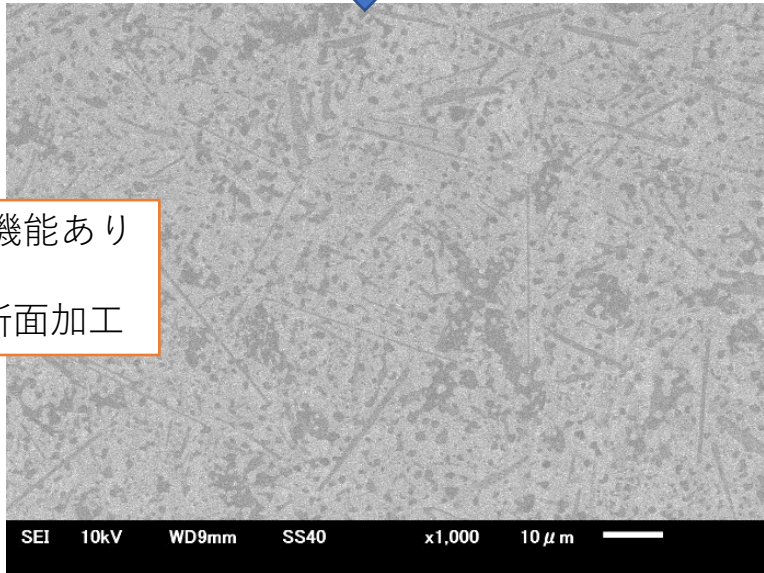
通常の断面ミリングの他、回転ホルダーによる平面ミリングも可能

CCPの冷却効果について(試料：U-アロイ70)

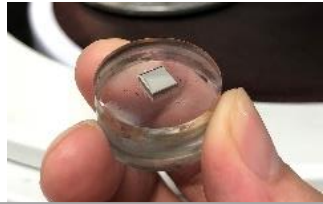
クライオ機能なし
8kV照射断面加工



クライオ機能あり
-120°C
8kV照射断面加工

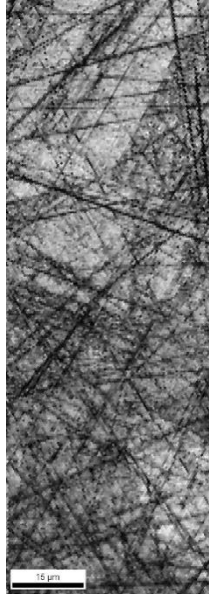


CCP 平面ミリングの効果について(試料：鉄鋼系材料)



EBSD of steel material after mirror polishing

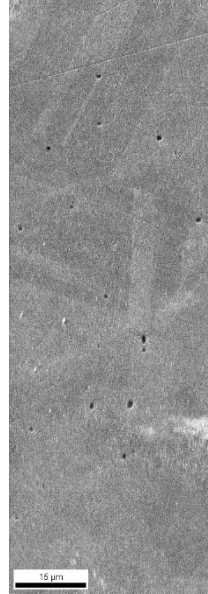
IQ map



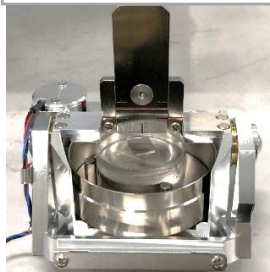
IPF map



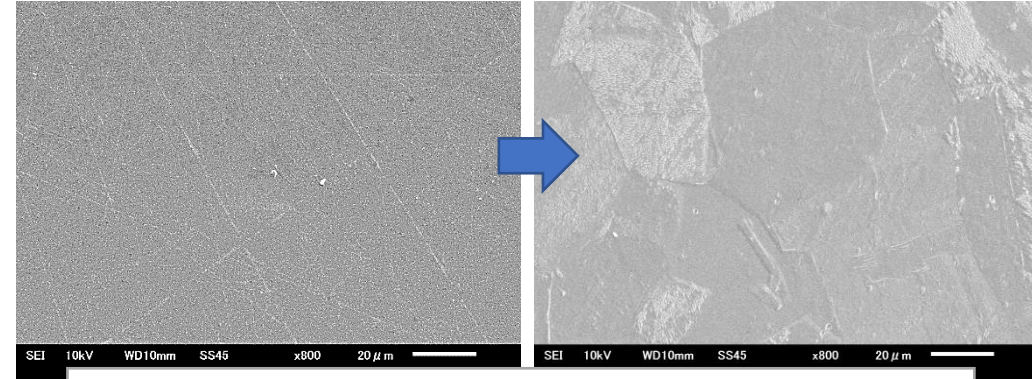
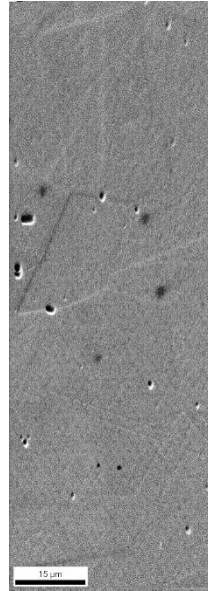
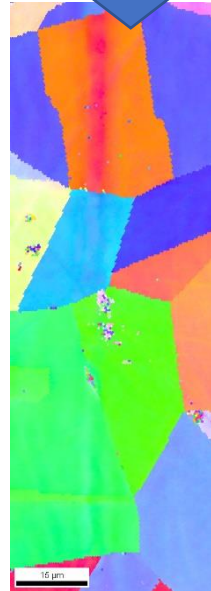
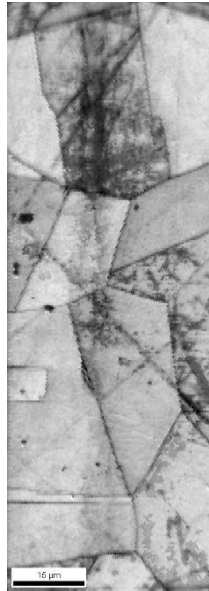
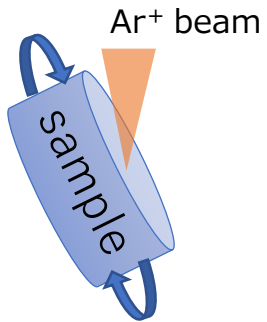
SEM image



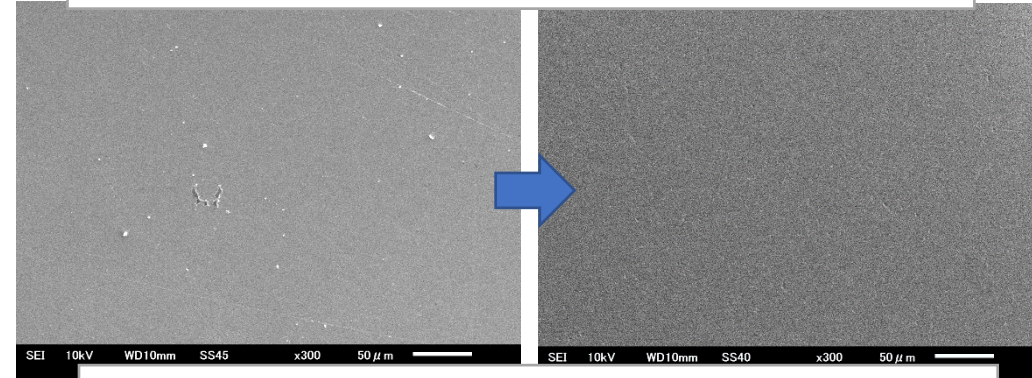
Large rotating sample holder



EBSD of the same sample after milling at an inclination of 85° at 4kV for 10 minutes



SUS sample mirror polished 70° tilted after 5kV10min. processing. SEM image of the same location.



SUS sample mirror polished 80° tilted after 4kV15min. processing. SEM image of the same location.